

EE143 Lab Week 5 Measurement Checklist:

1) Preliminary Measurements:

Furnace Temperature:	.
Control Wafer Sheet Resistance:	..

2) Pre-Deposition:

Time (sec)	..
Sheet Resistance	.

SOG Etch Time (sec):

Wet Oxidation:

Time (sec)	..
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Drive-In:

Time (sec)	..
Sheet Resistance	.

3) Measurements after Process Completion:

Intermediate Oxide Thickness (Nanospec):

Questions (In preparation for Lab Report 1):

Calculate Theoretical Oxide Thickness using Deal-Grove Model

Calculate surface dopant concentration from the sheet resistance after pre-deposition and drive-in.